CHE302 LECTURE II MEASUREMENT, TRANSMITTERS AND FILTERING

Professor Dae Ryook Yang

Fall 2001 Dept. of Chemical and Biological Engineering Korea University

CHE302 Process Dynamics and Control

Korea University 2-1

INTRODUCTION TO SENSOR

- What is Sensor?
 - Sensor converts the physical quantity to signal that can be recognized by other components such as display, transmitter and etc.

Sensor types

- Temperature: thermocouple, RTD, thermister
- Pressure: bellows, bourdon tube, diaphragm
- Flow rate: orifice, venturi, magnetic, ultrasonic, Coliolis effect
- Liquid level: float, differential pressure
- pH: pH electrode
- Viscosity: pressure drop across venturi or vane deflection
- Composition: density, conductivity, GC, IR, NIR, UV

MEASUREMENT DEVICE

• Transducer: Sensor+Transmitter

- Transmitter generates an industrial standard signal from the sensor output.
- Standard instrumentation signal levels
 - Voltage: 1~5VDC, 0~5VDC, -10~+10VDC, etc.
 - Current: 4~20mA (long range transmission with driver)
 - Pneumatic: 3-15psig
- Signal conversion
 - I/P or P/I transducer: current-to-pressure or vice versa
 - I/V (I/E) or V/I: current-to-voltage or vice versa
 - P/E or E/P: pressure-to-voltage or vice versa

• Analog-to-Digital (A/D) converter

- Continuous signal converted to digital signal after sampling
- Specification: sample rate, resolution (8bit, 12bit, 16bit)

```
CHE302 Process Dynamics and Control Korea University 2-3
```

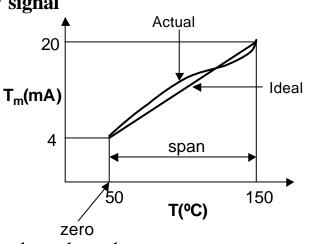
TRANSMITTERS

- Transmitter Gain (K_m): adjustable
 - Amplification ratio: (output span)/(input span)
- Span and Zero: adjustable
 - Span: magnitude of range of transmitter signal
 - Zero: lower limit of transmitter signal

Ex) Temp. Transmitter

$$K_{m} = \frac{(20mA - 4mA)}{(150^{\circ}C - 50^{\circ}C)} = 0.16 [mA/^{\circ}C]$$

span=100'C
zero=50'C



• Other functions: square-root extractor, ...

CHE302 Process Dynamics and Control

TEMPERATURE SENSORS

| Principle | Туре | Usable range (ºC) | Remarks |
|----------------------|------------------------------------|---------------------------------|--|
| Thermal Expansion | Gas expansion Liquid Bimetal | -230~600 -200~350 -50~500 | N2 Oil |
| Resistance | Pt-100 Thermistor | -200~500 <300 | Accurate, linear, self heating Cheap, inaccurate, nonlinear |
| EMF | Thermocouple | -200~1600 | Low sensitivity |
| | IC temp. sensor | -100~150 | High voltage, accurate, linear |
| Radiation | Pyrometer | Very wide | Noncontacting, need accurate calibration |

CHE302 Process Dynamics and Control

Korea University 2-5

| Temperature Sensor Attributes | | | | |
|-------------------------------|--------------------------------|---------------------------|------------------------------------|--|
| Criteria | Thermocouple | RTD | Thermistor | |
| Cost-OEM Quality | Low | High | Low | |
| Temperature Range | Very wide -450°F +4200°F | Wide -400°F +1200°F | Shot to medium -100°F +500°F | |
| Interchangeability | Good | Excellent | Poor to fair | |
| Long-term Stability | Poor to fair | Good | Poor | |
| Accuracy | Medium | High | Medium | |
| Repeatability | Poor to fair | Excellent | Fair to good | |
| Sensitivity (output) | Low | Medium | Very high | |
| Response | Medium to fast | Medium | Medium to fast | |
| Linearity | Fair | Good | Poor | |
| Self Heating | No | Very low to low | High | |
| Point (end) Sensitive | Excellent | Fair | Good | |
| Lead Effect | High | Medium | Low | |
| Size/Packaging | Small to large | Medium to small | Small to medium | |

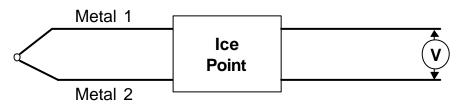
CHE302 Process Dynamics and Control

| Temperature Sensor Advantages/Disadvantages | | | | |
|---|---|--|--|--|
| Sensor | Advantages | Disadvantages | | |
| Thermocouple | Self-powered Simple Rugged Inexpensive Wide variety Wide range | Non-linear Low voltage Reference required Least stable Least sensitive | | |
| RTD | Most stable Most accurate More linear than thermocouple | Expensive Current source required Small A Low absolute resistance Self heating | | |
| Thermistor | High output Fast Two-wire ohms measurement | Non-linear Limited range Fragile Current source required Self heating | | |
| Infrared | No contact required Very fast response time Good stability over time High repeatability No oxidation/corrosion to affect sensor | High initial cost More complex/support electronics Spot size restricts application Emissivity variations affect readings Accuracy affected by dust, smoke and background radiation | | |

CHE302 Process Dynamics and Control

Korea University 2-7

THERMOCOUPLE



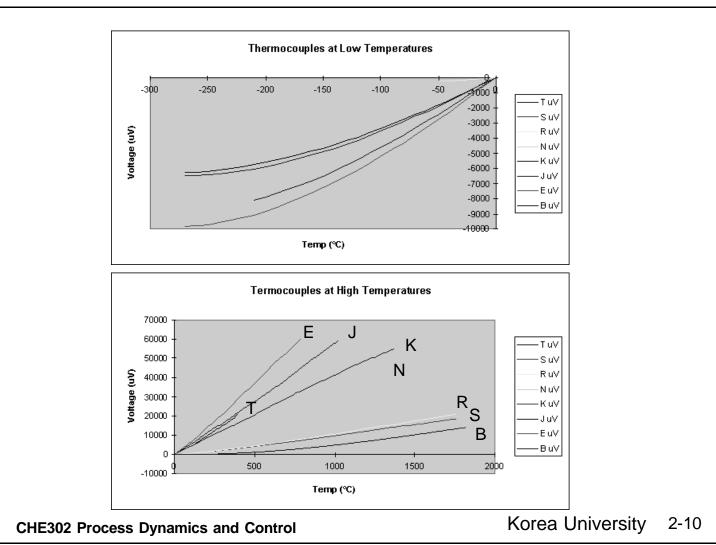
• Thermocouple Types

- Chromel alumel (K- type): most popularly used
- Iron- constantan (J- type): higher electromotive force (emf)
- Chromel constantan (E- Type): cryogenic temperature
- 13% Rh. Pt Pt (R- type): high temperature (> 900°C)
- Typical emf is about 0.041mV/°C for K type
 - Needs signal amplification
- Ice point can be a ice bath or an electronic device to compensate the ambient temperature.

| Thermocouple type | Overall Range (°C) | EMF (mV/ °C) |
|--------------------------|-----------------------|-----------------|
| B (Platinum / Rhodium) | 100~1800 | 0.01 |
| E (Chromel / Constantan) | -270~790 | 0.068 |
| J (Iron / Constantan) | -210~1050 | 0.054 |
| K (Chromel / Alumel) | -270~1370 | 0.041 |
| N (Nicrosil / Nisil) | -260~1300 | 0.038 |
| R (Platinum / Rhodium) | -50~1760 | 0.01 |
| S (Platinum / Rhodium) | -50~1760 | 0.01 |
| T (Copper / Constantan) | -270~400 | 0.054 |

- B,R,S: high temp. low sensitivity, high cost
- S: very stable, use as the standard of calibration for the melting point of gold (1064.43°C).
- N: improved type K, getting more popular
- T: cryogenic use
- Ref: <u>http://www.watlow.com/reference/refdata/TOP</u>
 http://www.picotech.com/applications/thermocouple.html

CHE302 Process Dynamics and Control



FLOW MEASUREMENT (1)

• Differential Pressure Cell

$$Q = \frac{C_d A_2}{\sqrt{1 - (A_2 / A_1)^2}} \sqrt{\frac{2 g_c \Delta P}{r}}$$

- ΔP : Delta P across the orifice
- A₁: area of flow pipe
- A₂: area of orifice
- C_d: orifice coefficient
- Maximum pressure drop should be < 4% of the total line pressure
- Selection of orifice size and delta P range is very important for the reading precision

CHE302 Process Dynamics and Control

 Current
 Voltage

 250Ω
 Power Source

 Flow
 Power Source

 Flow
 Power Source

 Plate
 Power Source



Korea University 2-11

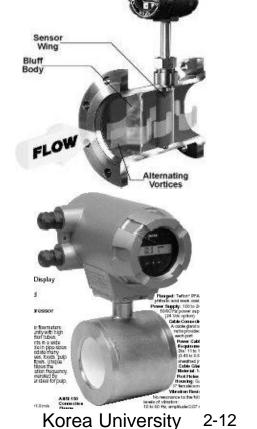
FLOW MEASUREMENT(2)

• Vortex Flow Meter

- The vortices create low and high pressure zones behind the bluff body.
- The vortex meter uses a piezoelectric crystal sensor to detect the pressure exerted by the vortices on the sensing wing.
- The piezoelectric crystal converts this vortex shedding frequency into electrical signals.

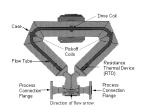
• Electromagnetic Flow Meter

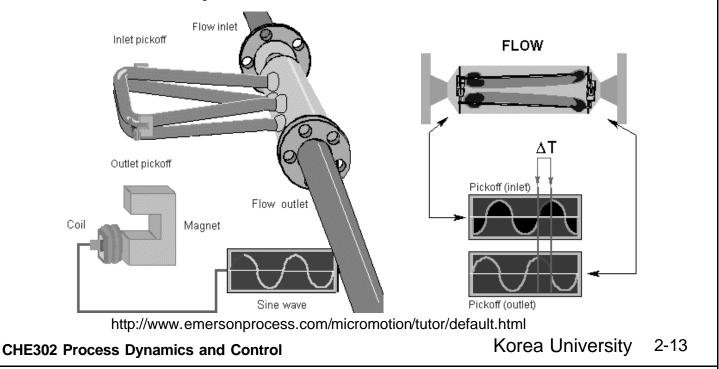
 Electrically conducting fluid passing through a magnetic field created by the device.



CORIOLIS FLOWMETER (3)

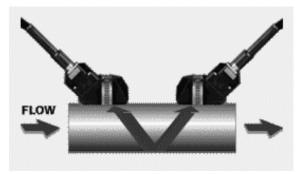
- Flow rate is measured by Coriolis effect (1835)
- Mass flowrate, vol. flowrate, temp. and density are simultaneously measured.





FLOW MEASUREMENT (4)

- Ultrasonic Flow Meter
 - High accuracy
 - No contact with flow



- Positive Displacement Flow Meter
 - Turbine, gear, wheels

• Thermal Dispersion Flow Meter

- Flow over heating coil will change temperature

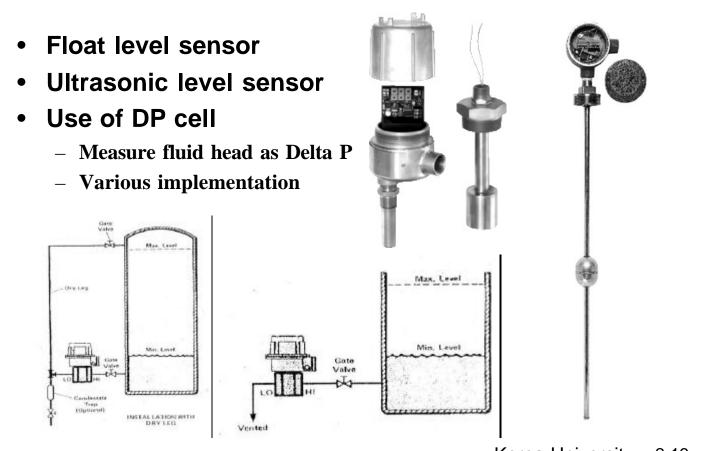
SELECTION OF FLOWMETERS

| Requirement | Orifice | Positive displace ment | Vortex | Electro- Magnetic | Acoustic | Coriolis |
|-----------------------|-------------------------------------|------------------------------|----------------------|--|-------------------------------------|--|
| accuracy | ±2~4% of full span | ±0.2~0.5% ofrate | ±1.0% ofrate | ±0.5% ofrate | ±1~5% of full span | ±0.5% ofrate |
| Press. loss | medium | high | medium | none | none | low |
| Initial Cost | low | medium | high | high | high | very high |
| Maintenance cost | high | medium | medium | low | low | low |
| Application | Clean,dirty liq.; some slurry | Clean viscous liq. | Clean,dirty liq.; | Clean,dirty viscous conductive liq. and slurry | Dirty, viscousliq. and slurry | Clean,dirty viscousliq. and some slurry |
| Upstream pipe size | 10~30 | None | 10 to 20 | 5 | 5 to 30 | none |
| Viscosity effect | high | high | medium | none | none | none |
| Rangeability | 4 to 1 | 10 to 1 | 10 to 1 | 40 to 1 | 20 to 1 | 10 to 1 |

CHE302 Process Dynamics and Control

Korea University 2-15

LEVEL MEASUREMENT



CHE302 Process Dynamics and Control

OTHER MEASUREMENTS

Composition measurements

- Expensive
- Long time delay
- High to maintenance cost
- Gas Chromatography
- IR, NIR, Raman, UV spectrophotometer
- pH sensor electrode: concentration of [H+]

• Secondary Measurements

- Density or temp. for binary composition

• Soft Sensors

- Estimated by a model based on other measurements

CHE302 Process Dynamics and Control

Korea University 2-17

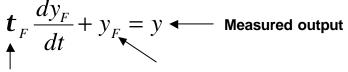
FILTERING

• Noise Source

- Process nature (turbulence, vibration, oscillation...)
- Various noise source from environment
- Power line, electromagnetic force, etc.

• Removing noise

- Analog filter



Filter time constant Filtered output

- First-order filter_analogy

$$t_F \frac{y_F - y_F^0}{\Delta t} + y_F = y$$
 Previous filtered output

$$y_F = a y_F^{0} + (1-a) y$$
 where $a = \frac{t_F / \Delta t}{1 + t_F / \Delta t} (0 < a < 1)$

CHE302 Process Dynamics and Control

- The filter behaves as an interpolation between the measured output and previous filtered output.
- If a=1, the measured output is ignored. (constant)
- If a =0, the filtered output is same as the measured output (no filtering)
- If $t_F = 0, a = 0$ and no filtering is achieved.
- If $t_F = \mathbf{X}$, a = 1 and the measured output is ignored.
 - **\mathbf{P}** As t_F increases, heavier filter is applied.

